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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Kiyoshi MOTEKI & Satoru OSHIKAWA**

Application No.: **09/856,384**

Filing Date: **May 21, 2001**

For: **Optical Apparatus, Exposure Apparatus, Laser Light Source, Gas Supply Method, Exposure Method, and Device Manufacturing Method**

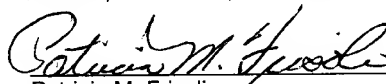
Group Art Unit: **2851** ✓

Examiner: **Kim, Peter**

Attorney Docket No. **25,096-USA**

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on July 22, 2003.

  
Patricia M. Frisoli

**Mail Stop Non-Fee Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450**

**Response To Office Action of 6/23/2003**

Sir:

This is in response to the Office Action dated June 23, 2003.

Claims 1-37 stand subject to restriction/election. Applicant is required to elect an invention to which the claims must be restricted. The claims have been grouped as follows:

Group I, claims 1-26

Group II, claim 27

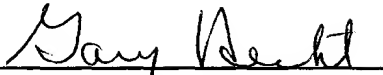
Group III, claims 28-36.

Appl. No. 09/856,384  
Paper dated 7/22/03  
Reply to Office Action of June 23, 2003

Applicant elects the claims of Group I: claims 1-26.

Respectfully submitted,

Date: July 22, 2003

  
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